

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masahiko NAKAMORI et al.  
App. No : 10/536,621  
Filed : May 26, 2005  
For : POLISHING PAD AND METHOD OF  
PRODUCING SEMICONDUCTOR  
DEVICE  
Examiner : Sylvia R. MacArthur  
Art Unit : 1792  
Conf # : 9275

AMENDMENT ACOMPANYING RCE

**Mail Stop Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Office Action mailed Jun 2, 2008, and the Advisory Action mailed August 20, 2008, please reconsider the present application on light of the following amendments and comments.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 5 of this paper.